

Lithium-Ion Electrolytic Substrates for sub-1 V High-Performance TMD Transistors and Amplifiers

Supporting Information

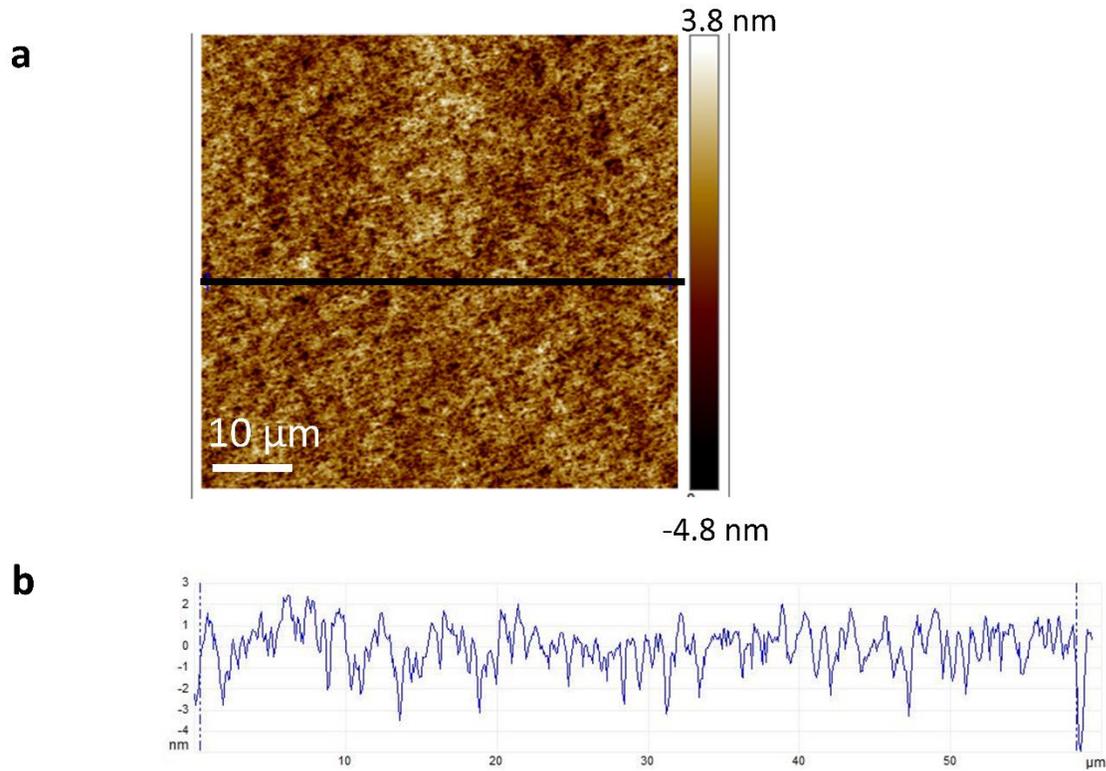
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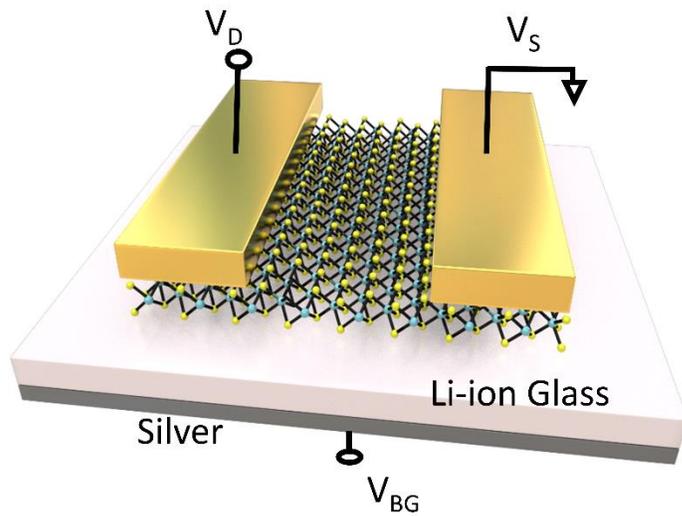
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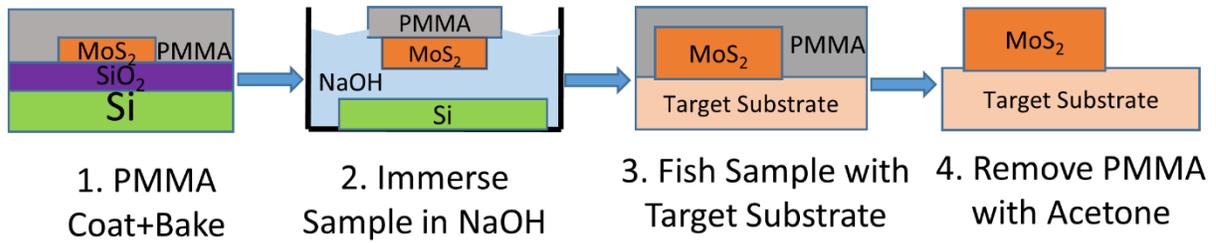
Supplementary Figures



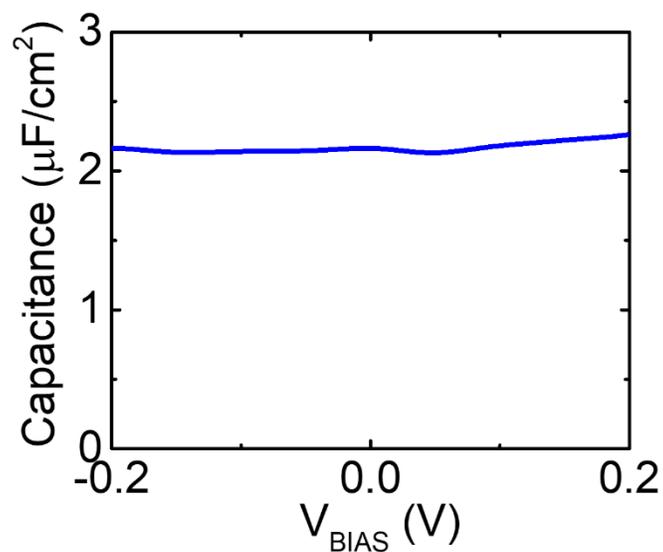
Supplementary Figure S1. AFM image of Li-ion glass substrate surface. (a) A scan of 60 μm by 60 μm area randomly selected to obtain substrate roughness. The average and RMS roughness are ~ 0.93 nm and ~ 1.19 nm, respectively. (b) The line scan for roughness along the black line in (a).



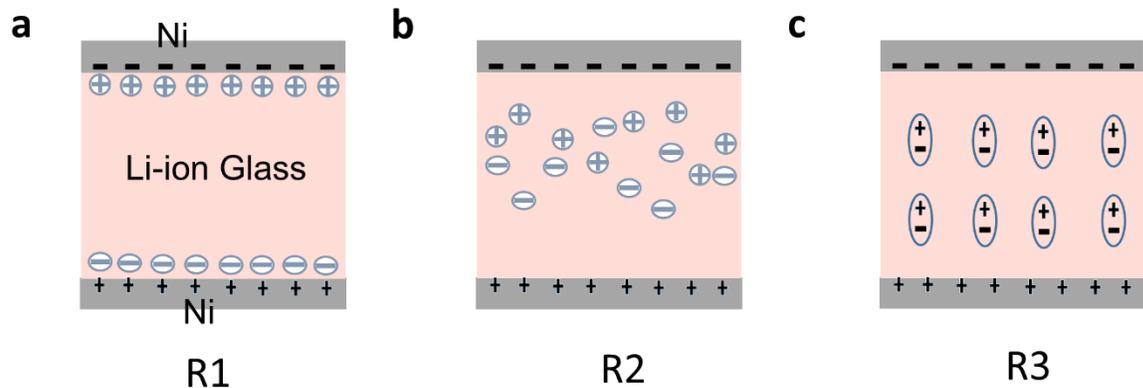
Supplementary Figure S2. Schematic of TMD back-gate transistor. Li-ion solid electrolyte works as back-gate dielectric/substrate and silver paint as a back-gate metal. The bias at the back-gate, drain and source is labeled as V_{BG} , V_D and V_S , respectively. Source is grounded whereas DC voltage is applied to the drain and gate terminals. Ni (Pd) is used as source/drain contact metals for MoS_2 (WSe_2) unless otherwise stated.



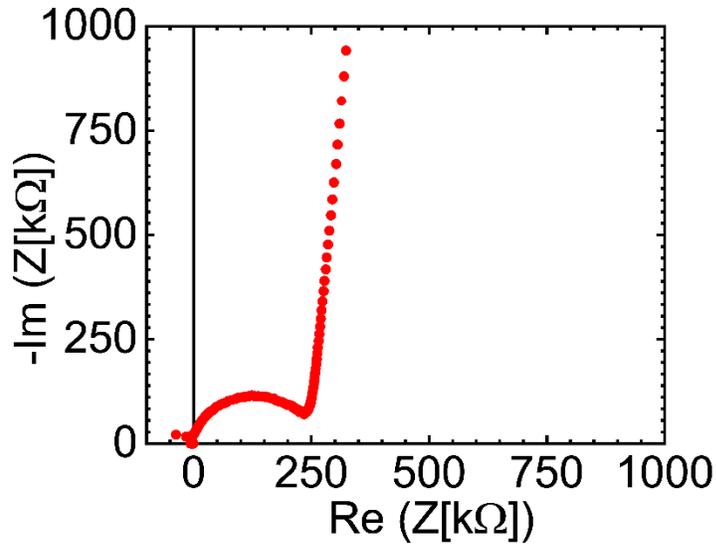
Supplementary Figure S3. Schematic of wet transfer method (not drawn to scale). The process involves i) delamination of MoS₂ from growth substrate using NaOH etchant, ii) fishing it onto target (Li-ion glass) substrate, iii) removal of PMMA and finally iv) anneal the sample.



Supplementary Figure S4. Quasi-static capacitance voltage characteristics of a Li-ion glass substrate. Ni (20 nm) is used as both top and bottom electrode. The data is obtained by using B1500 semiconductor parameter analyzer. We note an average value of capacitance is equal to 2.15 $\mu\text{F}/\text{cm}^2$.

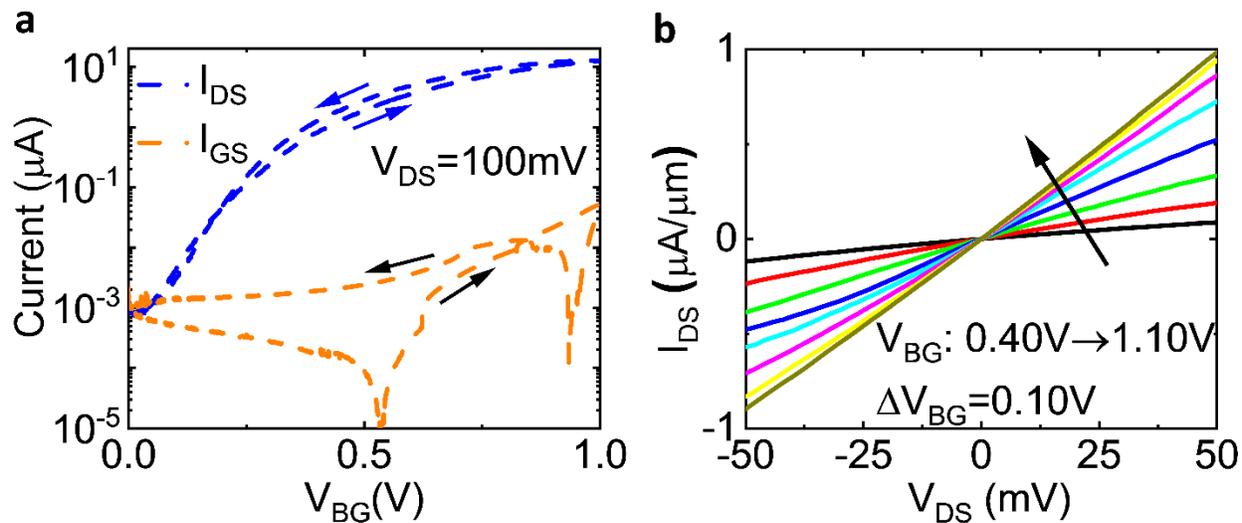


Supplementary Figure S5. Various regions of operation of Li-ion solid electrolyte. The frequency spectrum can be divided into 3 distinct regions: i) R1 where EDL is formed, ii) R2 where ion migration dominates, and iii) R3 where the bulk Li-ion glass works as a dielectric. Schematic diagram of (a) R1, (b) R2, and (c) R3 region. (a) R1 is in the frequency range <1.3 kHz where EDL is formed and the phase angle is close to -83° . (b) R2 ranges from ~ 1.3 kHz to ~ 89 kHz where ion migration dominates. (c) R3 frequencies are above 89 kHz where the bulk Li-ion glass works as a dielectric.

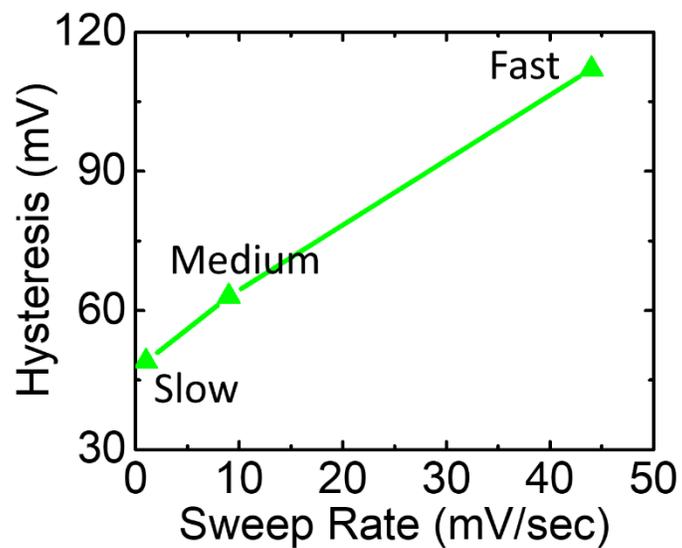


Supplementary Figure S6. Nyquist plot calculated from the data of experiment in Fig. 1f.

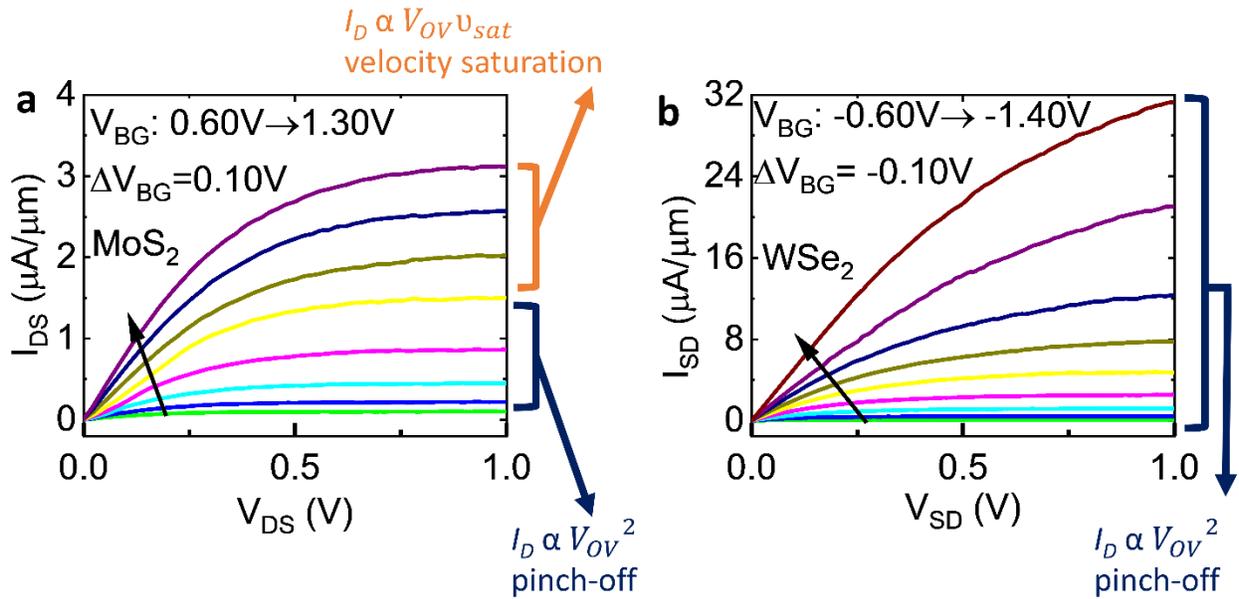
The resistance, and consequently the conductivity, was calculated from $\text{Re}(Z[\Omega])$ in the semi-circle ($R = 2.49 \times 10^5 \Omega$) using $\sigma = \frac{1}{R} \frac{d}{A}$, where $A = 165 \mu\text{m} \times 165 \mu\text{m}$ is the area of electrode and $d = 150 \mu\text{m}$ is the distance between the two electrodes.



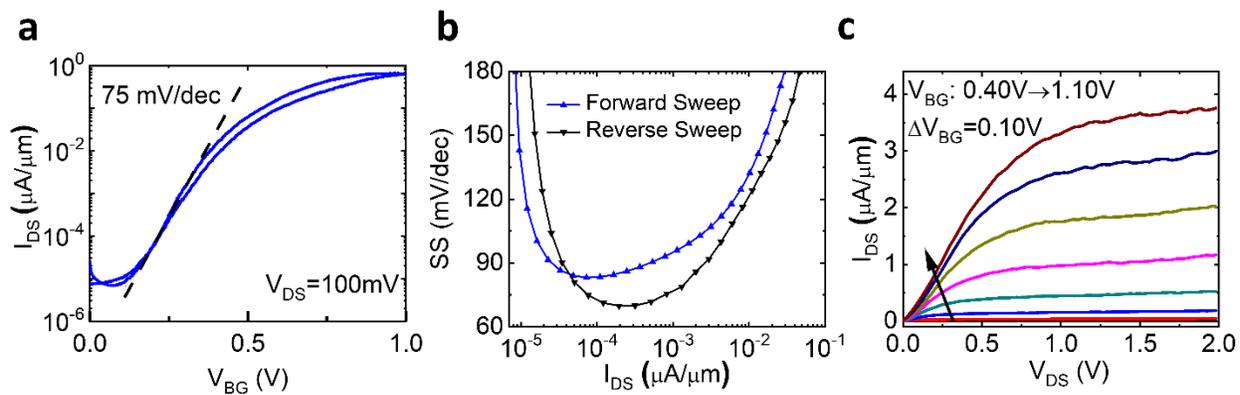
Supplementary Figure S7. Electrical transport characteristics of a CVD MoS₂ FET. (a) Gate leakage current vs. back gate (V_{BG}) voltage for monolayer CVD MoS₂ FET ($L=1\mu\text{m}$, $W=5\mu\text{m}$). (b) Output characteristics for small V_{DS} at different back-gate voltages for the same FET.



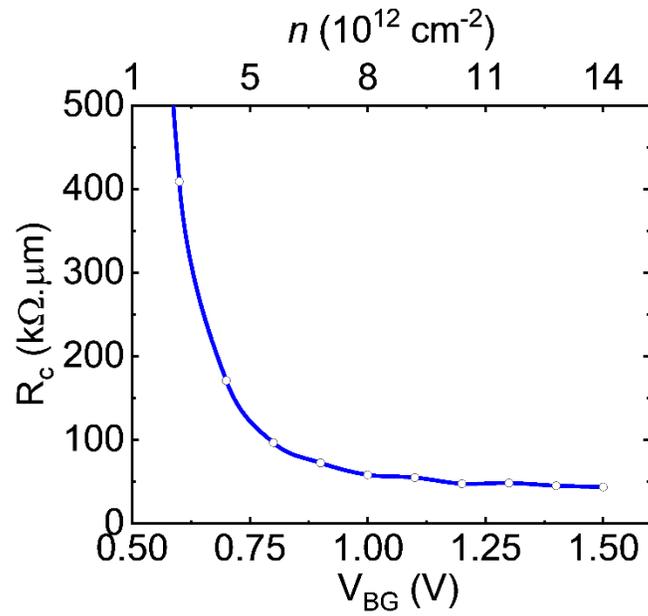
Supplementary Figure S8. Hysteresis voltage vs. sweep rate. In this work, fast, medium and slow speed correspond to the sweep rates of 44 mV/sec, 9 mV/sec and 1 mV/sec, respectively.



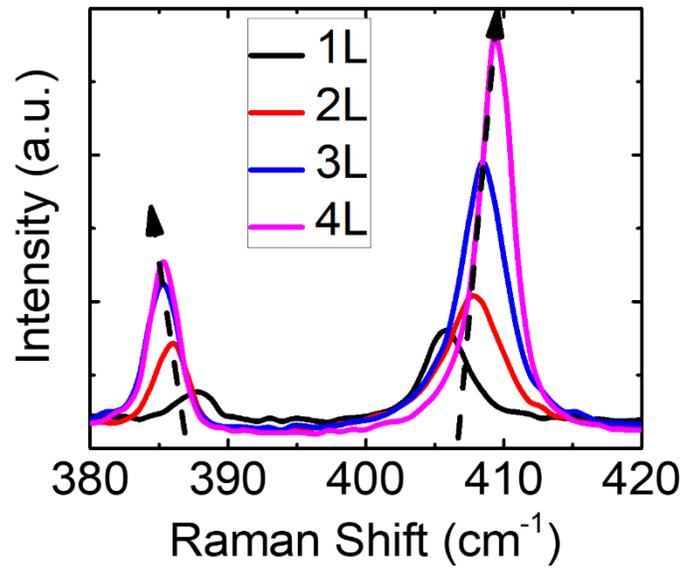
Supplementary Figure S9. Drain current saturation in TMDs with pinch-off/velocity saturation. (a) I_D - V_D characteristics of a MoS₂ FET. The saturation current is due to pinch-off up to a back-gate voltage of 1.00 V and after that it can be attributed to velocity saturation. Saturation current follows quadratic ($I_{D,sat} \propto V_{OV}^2$) and linear ($I_{D,vsat} \propto V_{OV}v_{sat}$) relationship with gate overdrive voltage ($V_{OV}=V_{BG}-V_{TH}$) for pinch-off and velocity saturation, respectively. (b) I_D - V_D characteristics of a WSe₂ FET. The saturation is due to pinch-off in the measured gate voltage range (V_{BG} up to -1.4 V). The absence of velocity saturation may be attributed to a higher critical field for WSe₂ FET on Li-ion glass substrate.



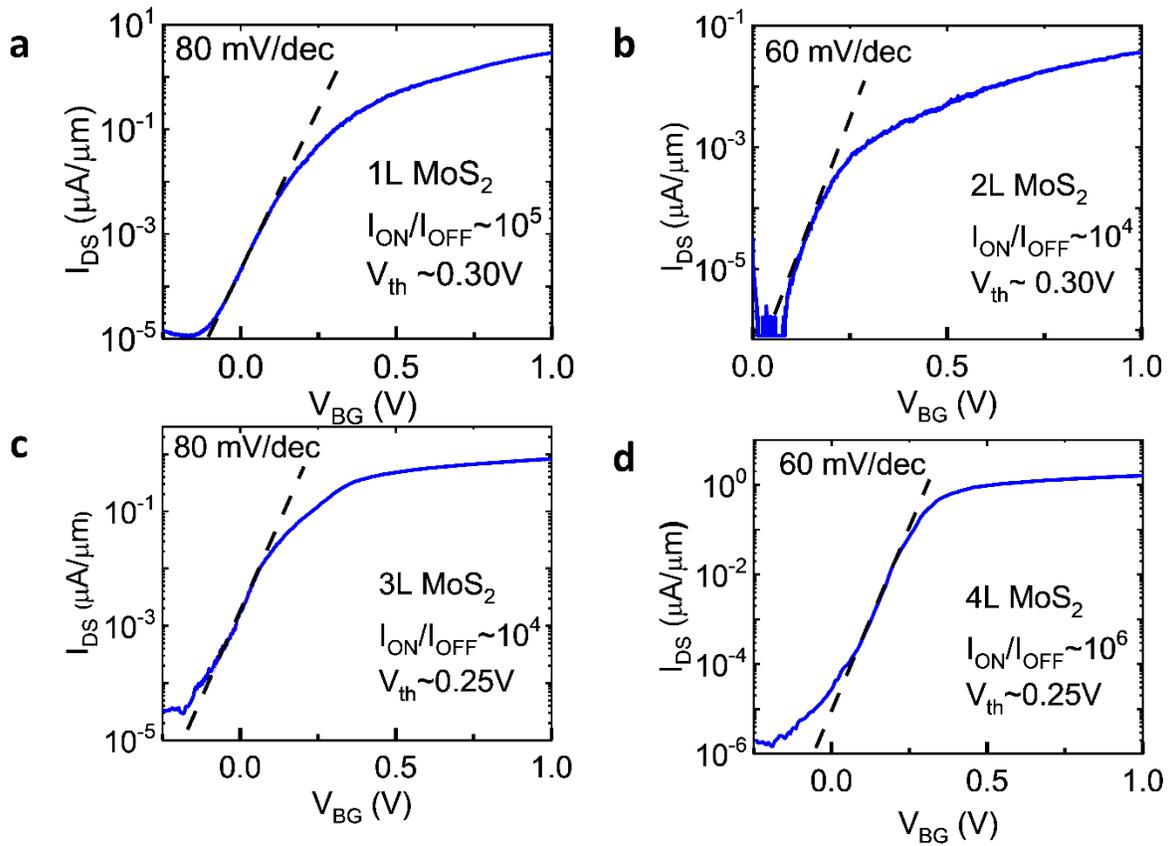
Supplementary Figure S10. Electrical transport characteristics of monolayer CVD MoS₂ FET (L=1.2 μm , W=5 μm). (a) Transfer characteristics at $V_{DS}=100\text{mV}$. (b) SS vs. I_{DS} . SS_{\min} are 83 mV/dec and 70 mV/dec for FW and BW sweeps respectively. (c) Output characteristics for different gate voltages.



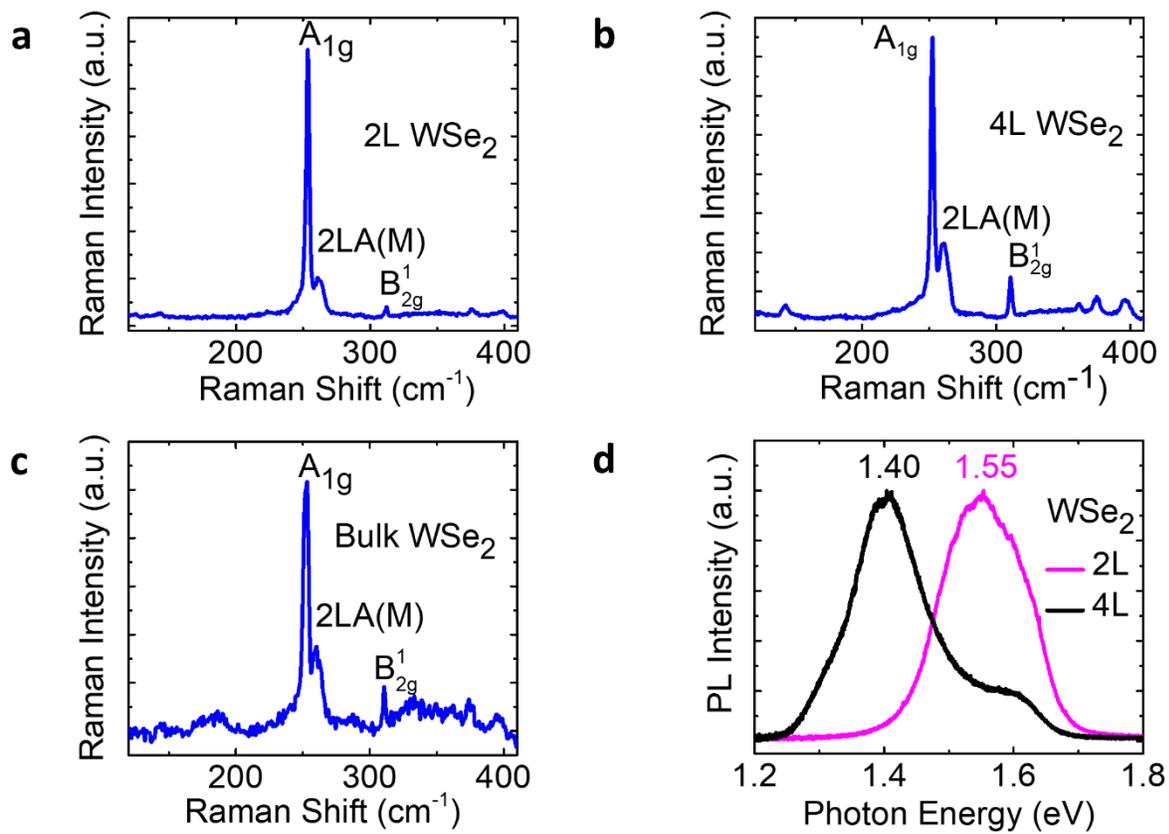
Supplementary Figure S11. Measured R_c vs. n (V_{BG}) for a single layer CVD MoS₂ transferred on Li-ion glass. R_c reaches $\sim 40 \text{ k}\Omega \cdot \mu\text{m}$ for $n > 10^{13} \text{ cm}^{-2}$ or $V_{BG} > 1.25 \text{ V}$, extracted using four probe technique. The contact metal is Ni.



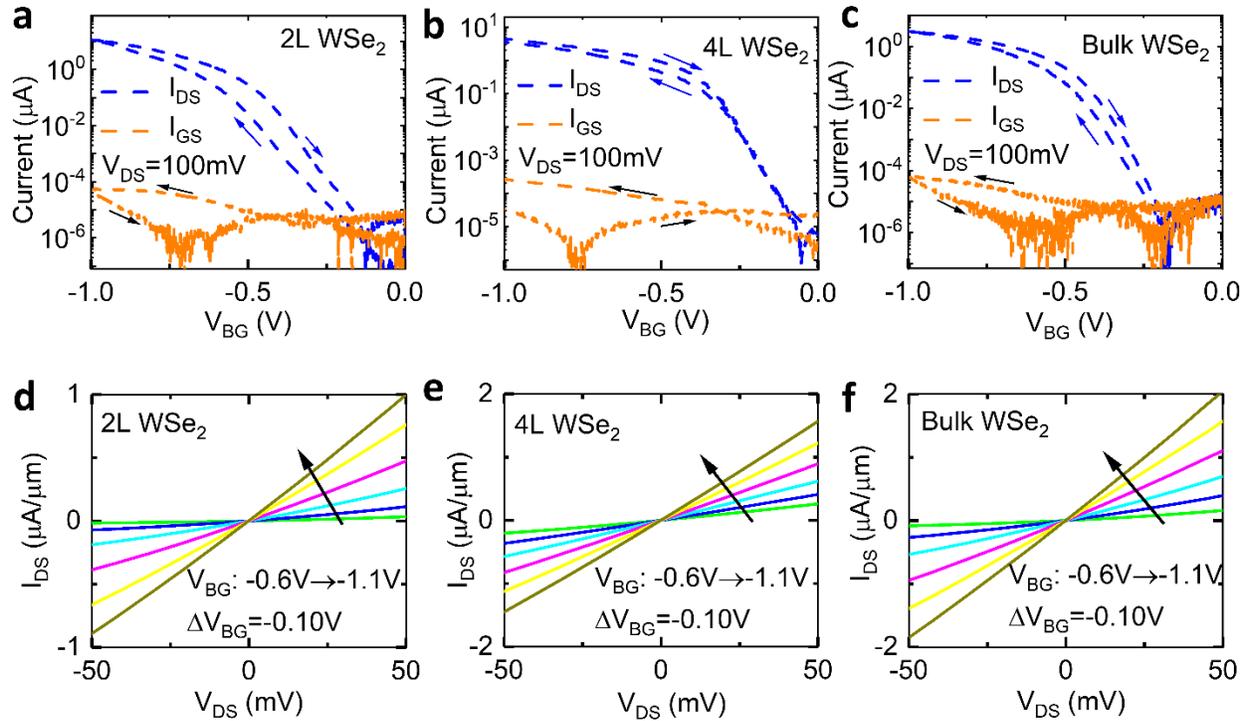
Supplementary Figure S12. Raman spectrum for 1L, 2L, 3L and 4L exfoliated MoS₂. Peak separation (distance between A_{1g} and E_{2g} peaks) agrees well with the reported value in literature for various layer thick MoS₂.¹



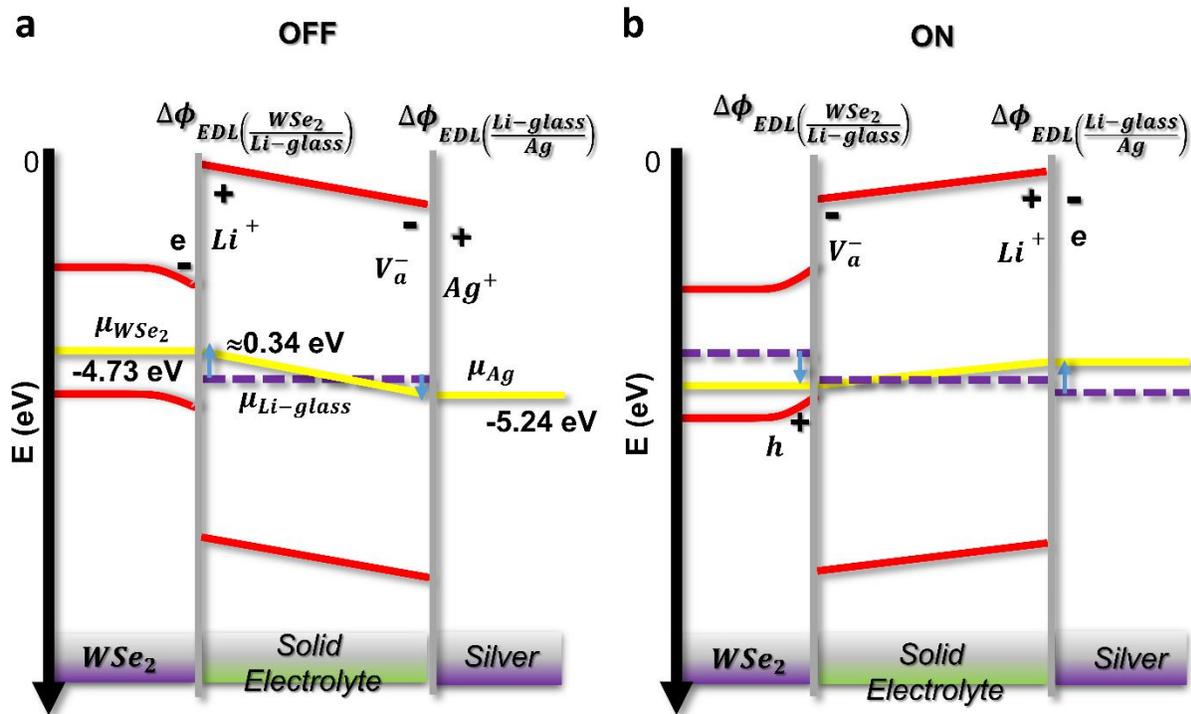
Supplementary Figure S13. Transfer characteristics of a (a) 1L, (b) 2L, (c) 3L and (d) 4L exfoliated MoS₂ FET. V_{th} , ON/OFF ratios and sub-threshold swings are in the range of 0.25 V-0.30 V, 10^4 - 10^6 , and 60-80 mV/dec, respectively for various layer thick MoS₂ FETs.



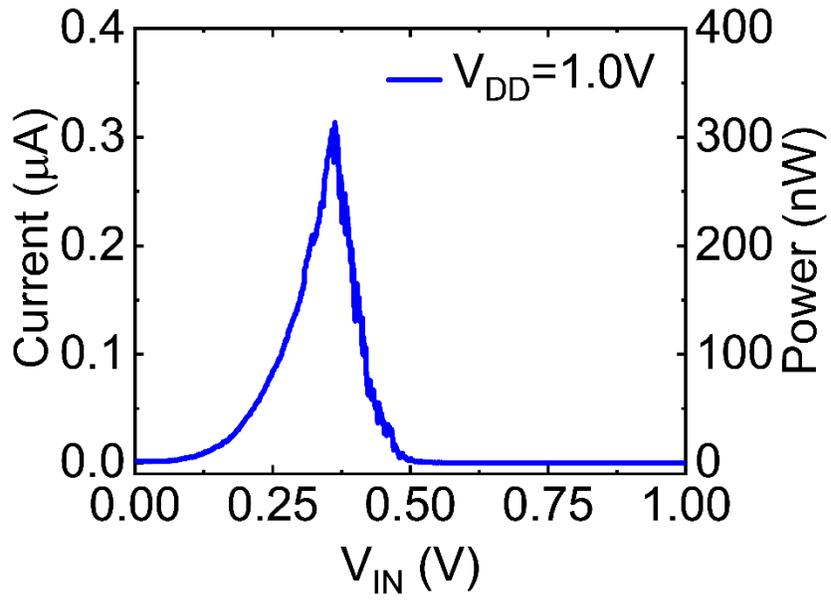
Supplementary Figure S14. Raman/PL spectrums for various layer WSe₂. Raman spectrum of exfoliated (a) 2L flake. Positions of A_{1g}, 2LA (M) and B_{2g}¹ modes are 253.5 cm⁻¹, 261.3 cm⁻¹ and 312.6 cm⁻¹, respectively. (b) 4L flake. Positions of A_{1g}, 2LA (M) and B_{2g}¹ modes are 252.6 cm⁻¹, 260.4 cm⁻¹ and 310.7 cm⁻¹, respectively. (c) Bulk flake (~14nm). Positions of A_{1g}, 2LA (M) and B_{2g}¹ modes are 253.1 cm⁻¹, 260.4 cm⁻¹ and 310.3 cm⁻¹, respectively. (d) Photoluminescence spectrum of the 2L and 4L WSe₂ flake. FWHM of 2L and 4L are 152 meV and 102 meV, respectively.



Supplementary Figure S15. Gate leakage current and linear I_D - V_D for various layer thick WSe₂. Drain current of (a) 2L, (b) 4L and (c) bulk WSe₂ FET. I_{DS} - V_{DS} relationship at small V_{DS} for a (d) 2L, (e) 4L and (f) bulk WSe₂ FET.

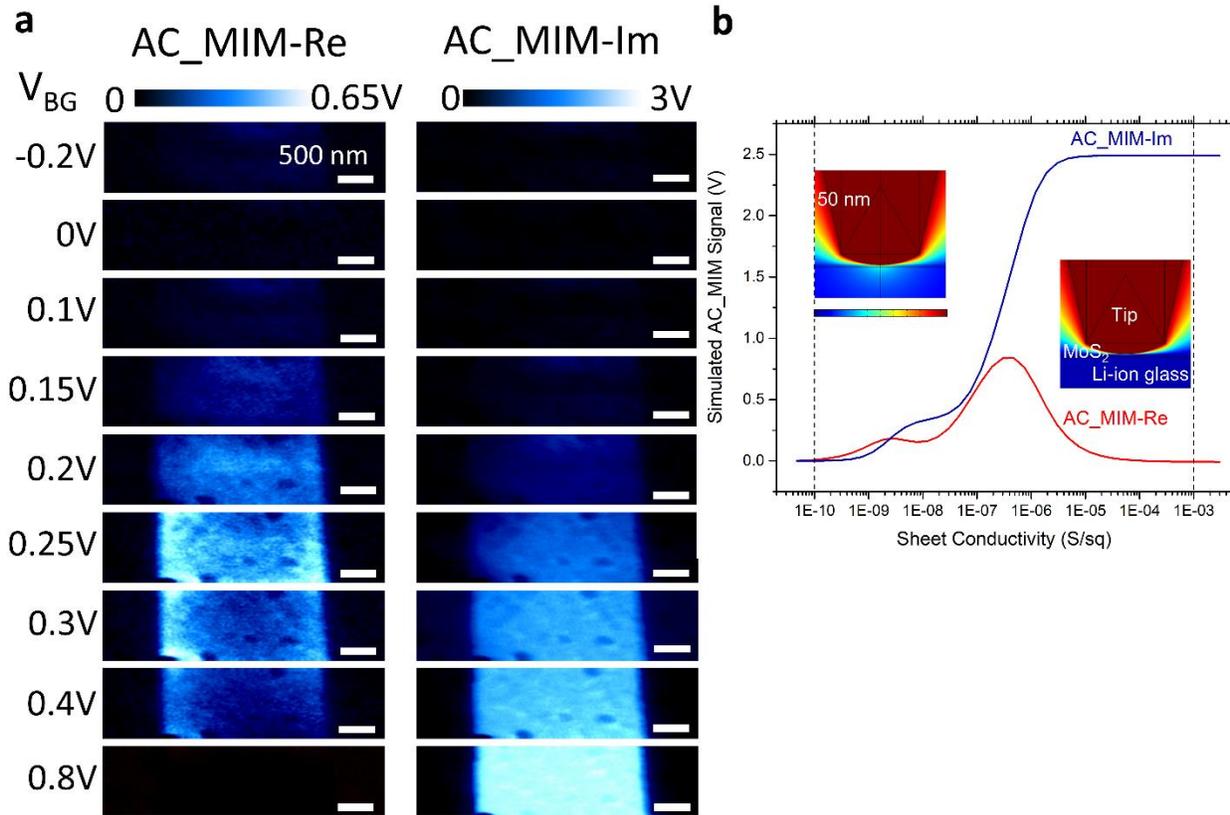


Supplementary Figure S16. Schematics illustrating the chemical potentials in ON and OFF state for a WSe₂ FET. The species in electrical contact within the FET back-gate to drain align their Fermi levels (electrochemical potential, not shown here) by the formation of EDLs which are represented with the chemical potentials (Fermi levels of the electrically insulated species). The purple dashed line and solid yellow line represents the initial and final state of the chemical potentials. (a) WSe₂ FET in OFF mode, the alignment of the Fermi levels is made spontaneously; the Li-ions diffuse to the surface of the Li-glass layer in electrical contact with WSe₂ leaving negatively charged vacancies behind (at the surface with Ag) constituting EDLs at both interfaces to allow Fermi levels alignment. (b) WSe₂ FET in ON mode after channel formation, V_{BG} to form the channel (0.34 V) was obtained indirectly in $I_{DS} - V_{BG}$ measurements in Fig. 3b, when the WSe₂ aligns its Fermi level with the Li-ion glass. The dynamic alignment between the Fermi level of Ag and Li-glass was obtained at approximately -0.17 eV (Fig. 3b) when the drain current is essentially negligible (no EDL at the interface of Li-ion glass/Ag).²



Supplementary Figure S17. Output current (static power) vs. input voltage of the inverter.

Static power ($Power = V_{DD} \times I_{OUT}$) is shown on the right axis of the same graph.



Supplementary Figure S18. MIM data of a MoS₂ FET on Li-ion substrate. (a) MIM maps of the selected channel region of the FET at different gate voltages. All scale bars are 500 nm. (b) Simulated AC_MIM signal as a function of the 2D sheet conductance σ_{sh} . The insets show the quasi-static potential distribution at $\sigma_{sh} = 10^{-10}$ and 10^{-3} S/ \square , respectively. The imaginary part of the signal monotonously increases with the sheet conductivity, while the real part of the signal reaches its maximum at $\sigma_{sh} \sim 10^{-7}$ S/ \square then drops back to zero. The evolution of the MIM signals with respect to the gate voltages is consistent with the simulation result.

Supplementary Table

Supplementary Table 1. Comparison with previous work. Comparison of this work with other realistic solid-state CMOS inverters based on TMD channel materials.

Reference	Substrate (Gate Dielectric)	n-MOS/p-MOS	DC Gain	V _{IN} (V)	V _{DD} (V)
This work	Li-ion glass (Li-ion glass)	MoS ₂ / WSe ₂	34	0 ~ +1	1
Atiye et al., ACS NANO, 10, 2015	Glass (50 nm Al ₂ O ₃)	MoS ₂ / MoTe ₂	33	0 ~ +1	1
June et al., ADVANCED MATERIALS, 29, 2017	Glass (50 nm Al ₂ O ₃)	MoTe ₂ / MoTe ₂	18	0 ~ +1	1
Stefano et al., ACS NANO, 11, 2017	SiO ₂ /Si (12 nm h-BN)	MoTe ₂ / MoTe ₂	3	0 ~ +1	1
Yann-Wen et al., NANOSCALE HORIZONS, 4, 2019	SiO ₂ /Si (3 nm SiO ₂ + 10 nm HfO ₂)	MoS ₂ /MoS ₂	16	0 ~ +2	2
Yang et al., 2D MATERIALS, 3, 2016	SiO ₂ /Si (20nm HfO ₂)	MoS ₂ /BP	2.7	0 ~ +2	2
Xidong et al., NATURE NANOTECHNOLOGY, 9, 2014	SiO ₂ /Si (20 nm HfO ₂)	WS ₂ / WSe ₂	24	0 ~ +2.5	N/P

N/P: data not provided

Supplementary Notes

Supplementary Note 1. Speed of Li-ion glass back-gated TMD FET

The speed of EDLT device operation is mainly dependent on the timescale of EDL formation, where the timescale can be reduced by increasing ion conductivity and/or electric field strength. A Li ion conductivity of approximately 0.22 mS/cm was obtained at room temperature by using Nyquist plot (see Supplementary Fig. S6), which agrees well with the expected value in Li-ion glass;³ ionic liquids, alternatively, have a conductivity on the order of 1 mS/cm.⁴ From the low-amplitude AC impedance analyzer data in Fig. 1f, a complete/partial EDL formation is observed up to a frequency of ~ 100 kHz, similar to the observed timescale (up to a hundred kHz) in ionic liquid/gel.^{5,6} The timescale for EDL formation can experimentally be improved further (\sim MHz) by using a higher amplitude DC pulse (few mV/nm), limited by the electrochemical window (voltage at which oxidation and reduction reactions take place in the electrolyte) of the electrolyte (> 4.3 V for solid electrolytes). Even going beyond (few hundreds mV/nm) the electrochemical window with a substantially short period of time to avoid electrochemical reactions, was theoretically found to induce EDL in a much shorter timescale (GHz), technologically relevant for electronics applications.⁷

Supplementary Note 2. Drain current saturation in Li-ion glass back-gated TMD FET

For lower overdrives ($V_{OV}=V_{BG}-V_{TH}$), the current saturates due to channel pinch-off near the drain and $I_{D,sat} \propto V_{OV}^2$, whereas for higher overdrives, carrier velocity saturates at lateral V_{DS} (and average lateral fields) lower than required to cause pinch-off and $I_{D,sat} \propto V_{OV}v_{sat}$. The crossover between the pinch-off and velocity saturation regimes will occur when the average lateral field $V_{OV}/L \approx 2v_{sat}/\mu_{eff}$.⁸

From the I_D - V_D output characteristics of MoS₂ FET (Supplementary Fig. S9), it is observed that the crossover between channel pinch-off and velocity saturation regions occurs approximately at an overdrive voltage of 0.6 V ($V_{BG}=1.0V$, $V_{TH}=0.4V$). Also, drain currents at saturation follows quadratic relationship with V_{OV} (channel pinch-off region) up to the crossover point ($V_{BG} \sim 1.00V$ or $V_{OV} \sim 0.6V$) and after that it follows linear (constant spacing) relationship (velocity saturation region). Interestingly, unlike MoS₂, no crossover between pinch-off and velocity saturation regimes for saturation current in WSe₂ FETs has been observed, even with the application of a comparatively higher back-gate voltage (up to -1.4 V) (Supplementary Fig. S9). This dissimilarity between Li-ion back-gated MoS₂ and WSe₂ FETs can be attributed to a comparatively higher critical field for velocity saturation in the latter, which contrasts with a theoretical prediction of a higher critical field ($E_{crit} \propto v_{sat}/\mu_{eff}$) of the former.⁹ This anomaly may be due to the strong effect of optical phonons in the Li-ion glass substrate on the channel transport, not considered in the theoretical work, and further elucidation on that requires a thorough and complex study of the substrate effect on the velocity saturation of various TMDs.

Supplementary Note 3. Unipolar conduction in Li-ion glass back-gated TMD FET

The contact resistance (R_c) with a Ni contact has been determined to be $\sim 40 \text{ k}\Omega\cdot\mu\text{m}$ at $n > 10^{13} \text{ cm}^{-2}$ using four probe technique (shown in Supplementary Fig. S11), similar to the reported values (10-100 $\text{k}\Omega\cdot\mu\text{m}$) for a SiO_2/Si back-gated single layer CVD MoS_2 with the same metal contact under the same deposition condition (e-beam, $\sim 10^{-6}$ Torr).¹⁰ In contrast, several orders of magnitude decrease in contact resistance with ionic liquid top-gating over conventional SiO_2/Si back-gate has been achieved,¹¹ which is ascribed to the significant reduction of Schottky barrier (SB) width down to the order of electrostatic screening length of ionic liquid ($\sim 1 \text{ nm}$) caused by the strong electrostatic action of the ions (in liquid) close to metal/semiconductor interface at higher gate voltage.¹² The significant reduction in SB width facilitates enhanced carrier injection of both electrons and holes via tunneling through the SB, thereby realizing hole channel conduction even in the presence of a relatively high Schottky barrier height (SBH) of hole ($\sim 1 \text{ eV}$) in MoS_2 FET.¹³ The evolution of hole branch due to strong band bending assisted by ionic liquid gating together with the inherently strong electron branch gives rise to ambipolar transport in ionic liquid top-gated MoS_2 FET.¹⁴

On the other hand, in back-gated solid electrolytic substrates, the ions are likely to be at least several screening lengths away from the metal/semiconductor interface since material and contact integration is not going to be as intimate as a liquid interface. In this case, band bending/SB narrowing will not be as significant as compared to ionic liquid. This, together with the negligible change in SBH for both electron ($\Phi_B \approx 0.18 \text{ eV}$) and holes ($\Phi_B \approx 1 \text{ eV}$) in pristine semiconductor/metal contact by gating,¹⁵⁻¹⁷ results in desirable unipolar electron branch in MoS_2 FET as observed in this work, consistent with a previous report.¹⁸

Supplementary References

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